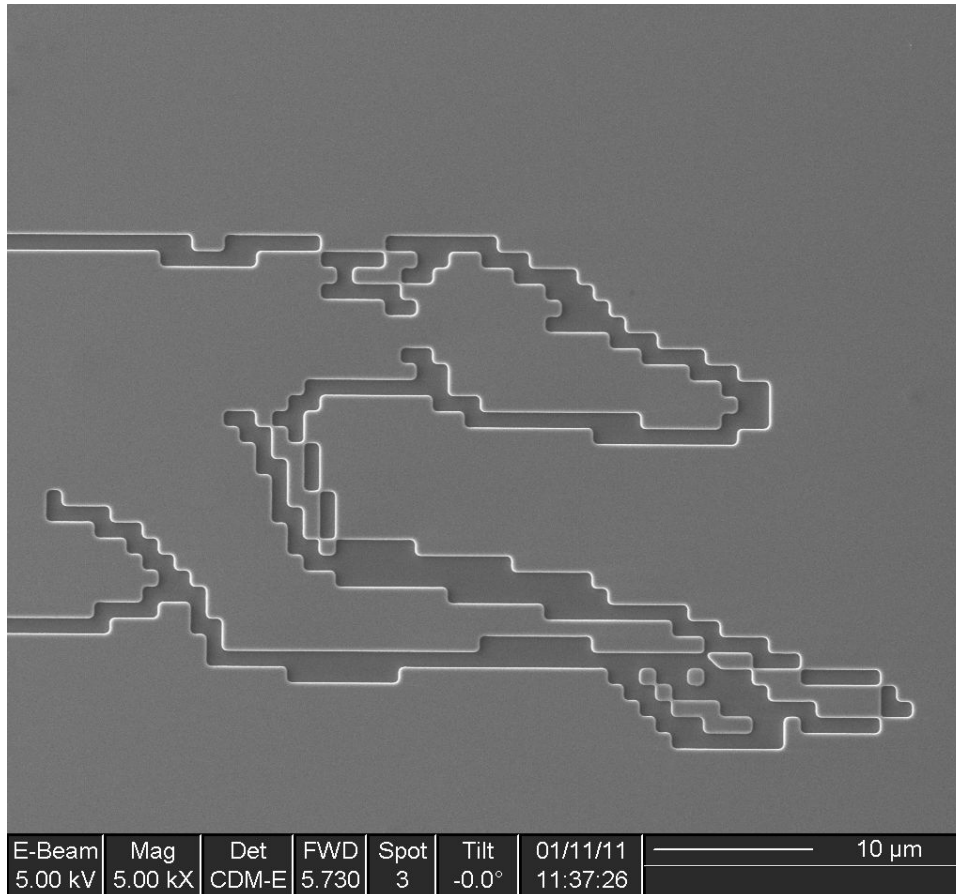
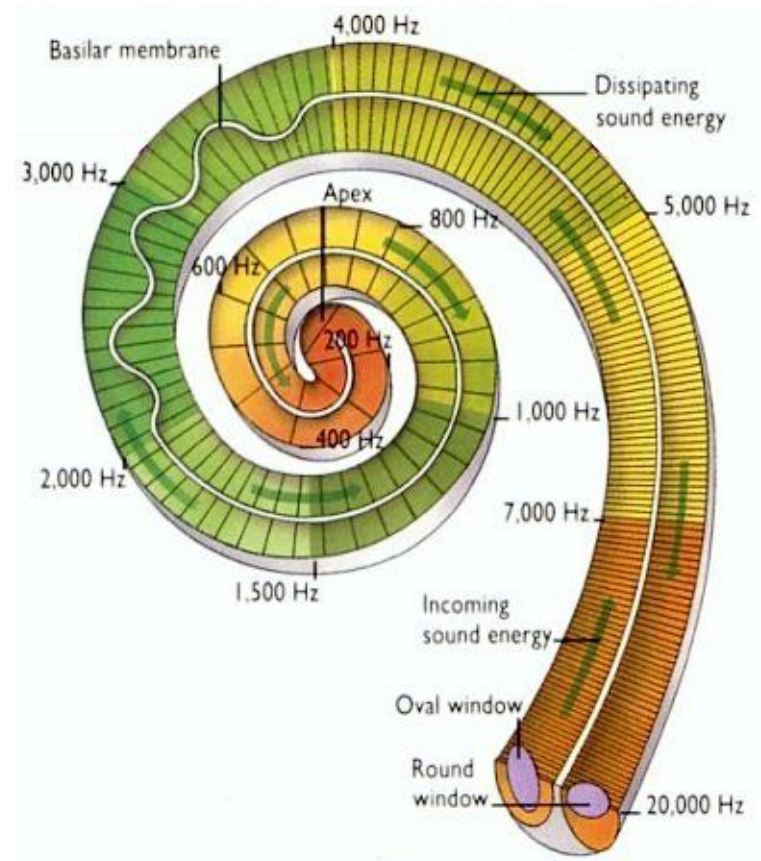
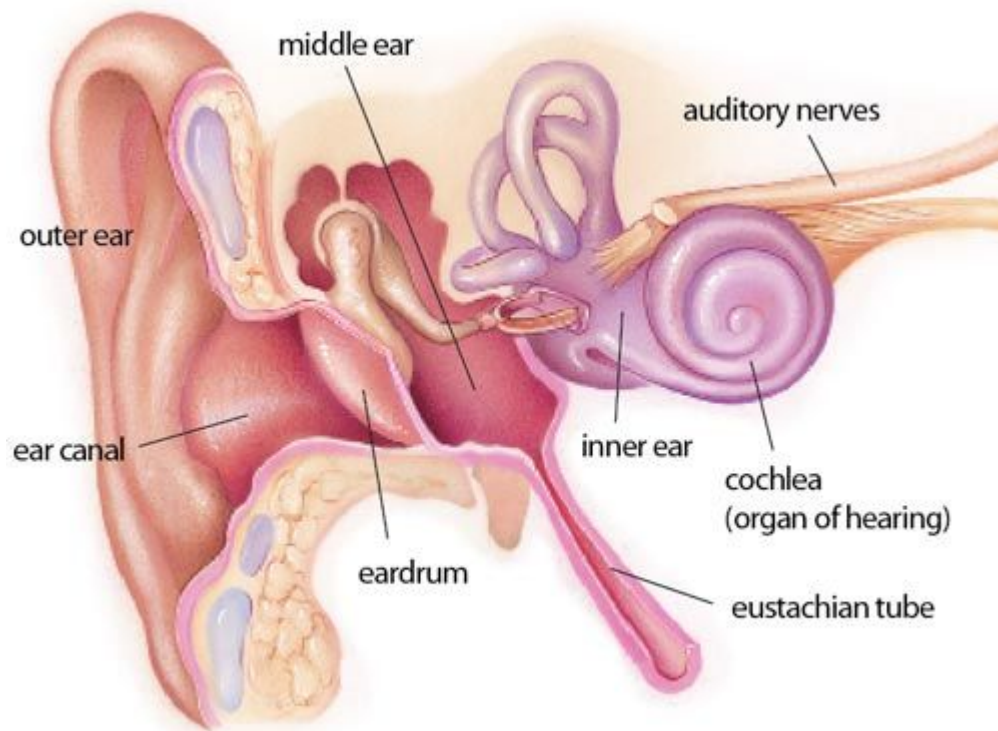


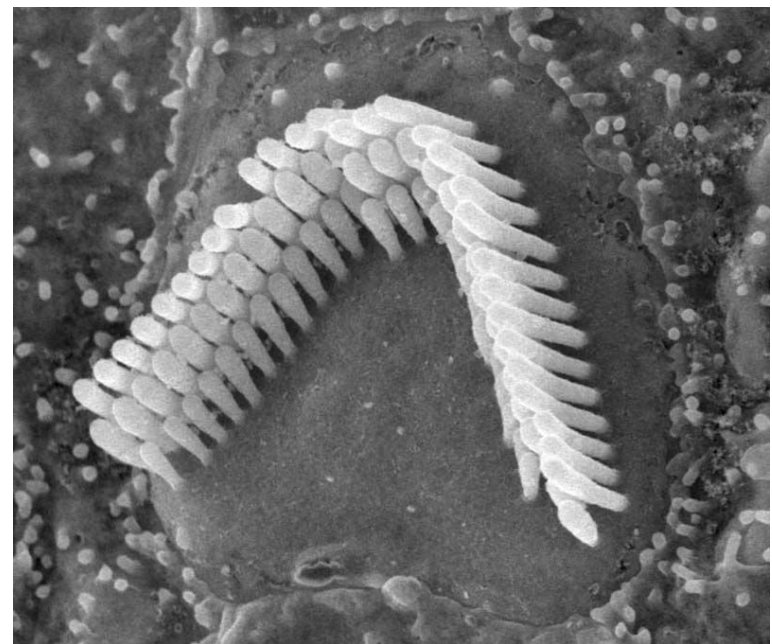
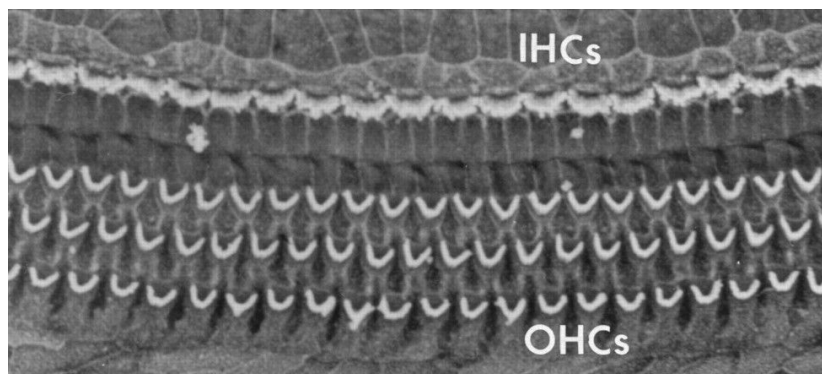
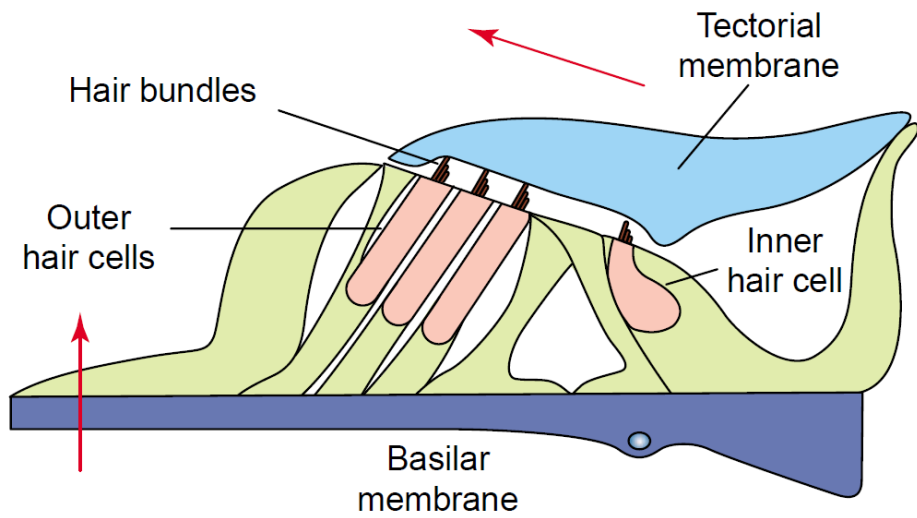
Green Light Meeting

Joey Doll

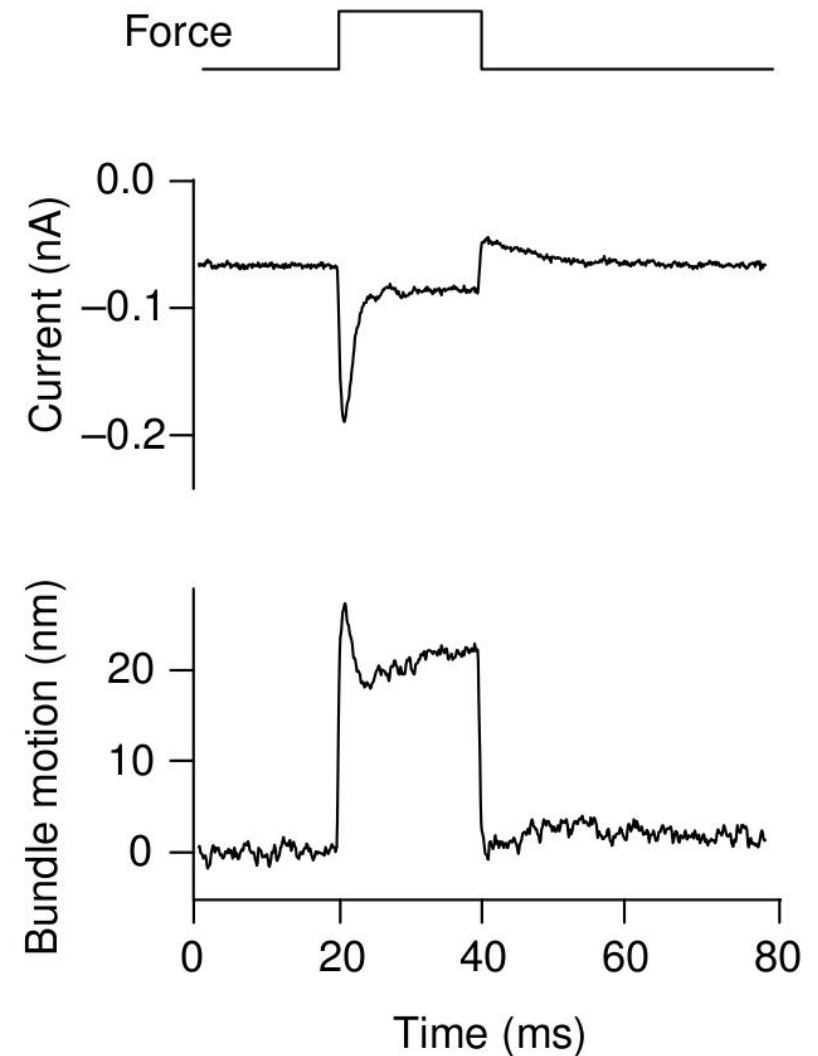
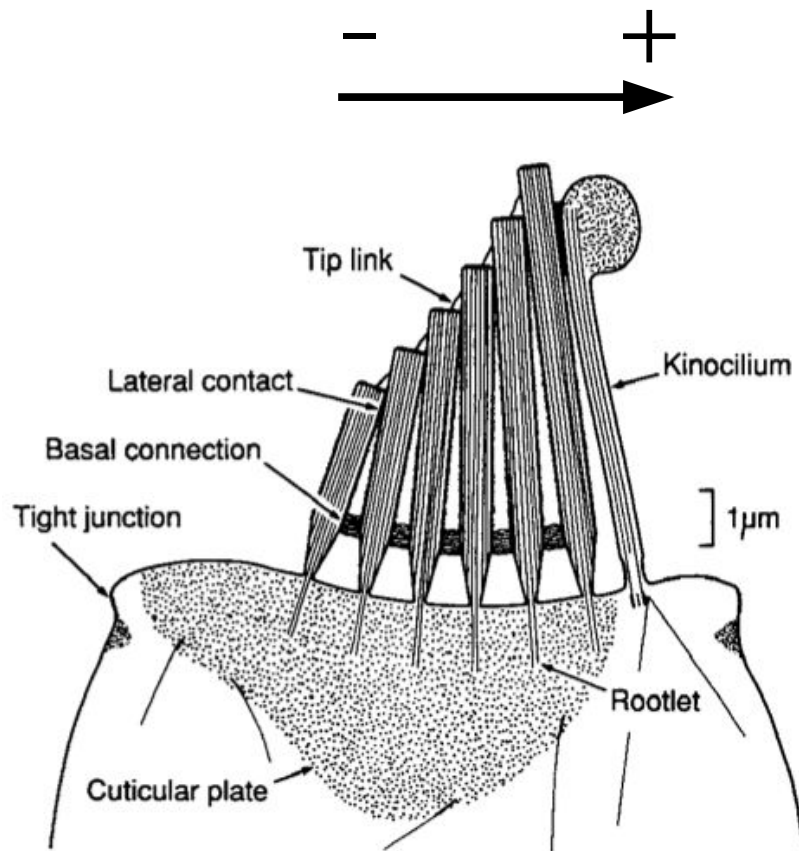
10/27/2011



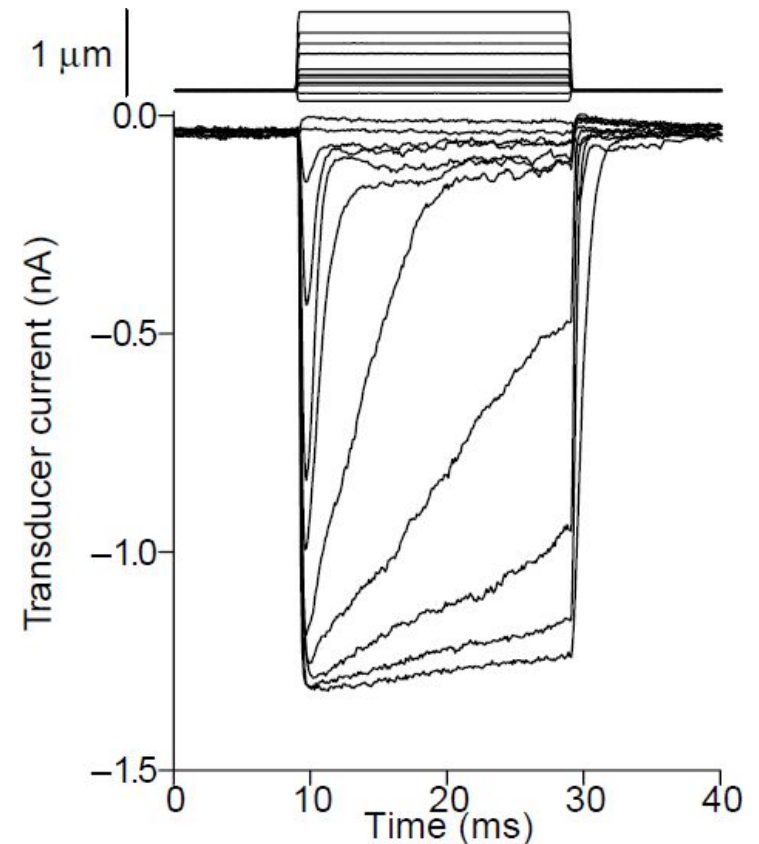
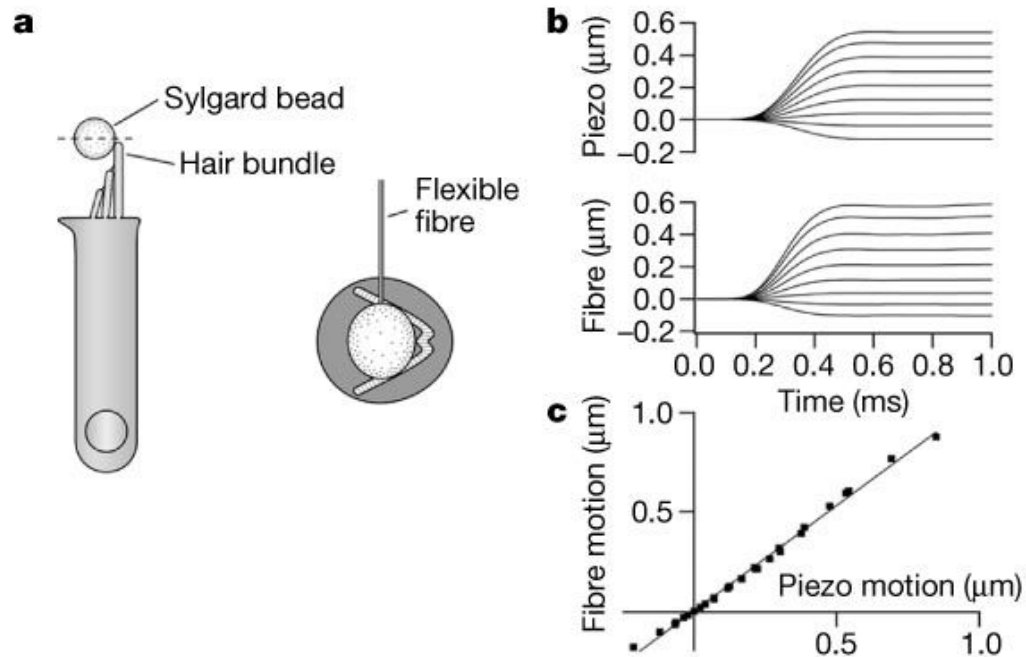




Hair Cells as Mechanical Transducers



Current Experimental Methods



Project image onto photodiode
Mechanics: 1 kHz, 1 mN/m
Kinetics: 5-10 kHz, >10 mN/m

Problem

Macroscale force probes are too slow
for mammalian hair cells

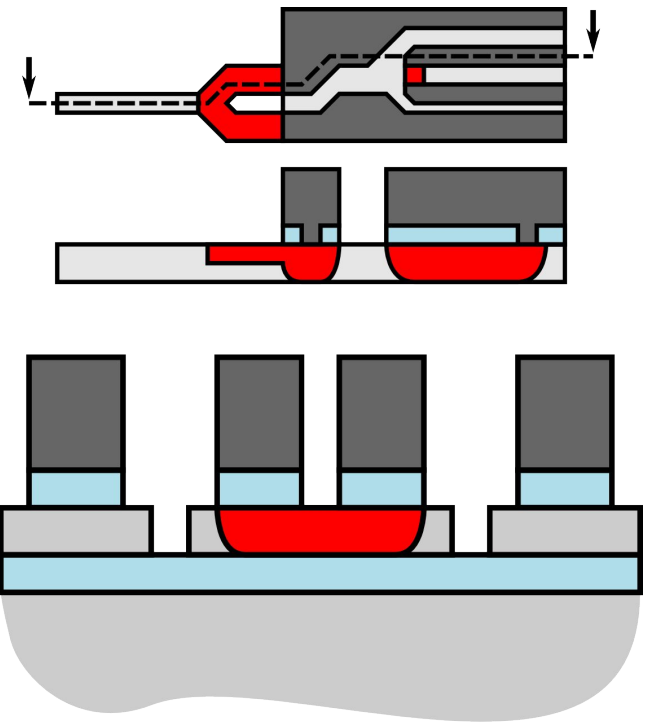
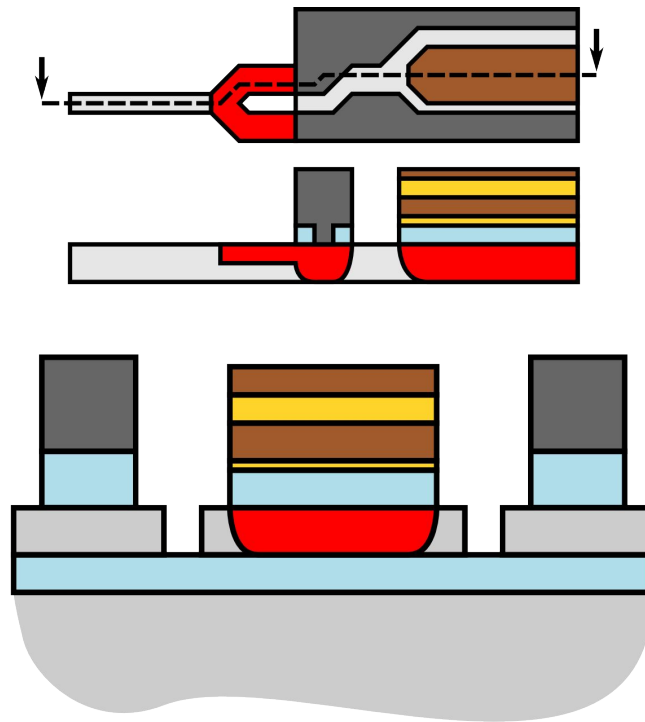
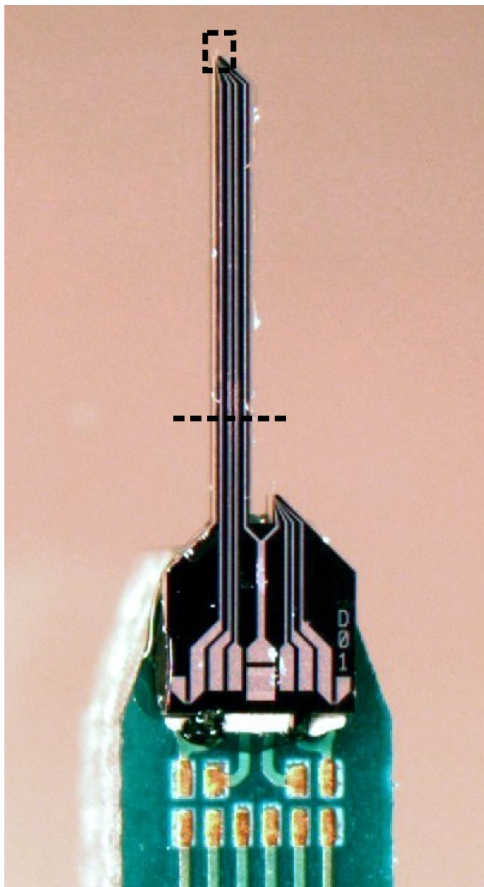
Design Targets







	Design #	l_c (μm)	l_{pr} (μm)	k (mN/m)	f_d (kHz)	t_r (μsec)	R_{pr} (k Ω)	MDD (nm)	MDF (pN)
Kinetics Mechanics	1	142	12.6	0.3	3.3	286	4.1	11	3.3
	2	96	9.5	1.0	9.7	60	3.2	6.3	6.2
	3	75	7.7	2.1	19	23	2.7	4.6	9.6
	4	61	6.6	3.9	32	11	2.4	3.6	14
	5	46	5.2	9.0	64	4.6	2.0	2.7	24
	6	35	4.1	20.4	124	2.0	1.6	2.1	42
	7	29	3.6	35.8	190	1.2	1.5	1.7	61

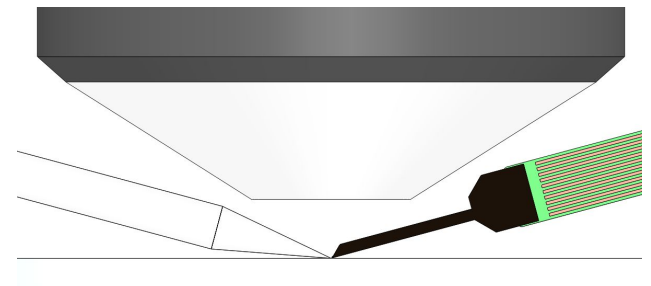
Device Design

Piezoelectric actuation (PRPE)

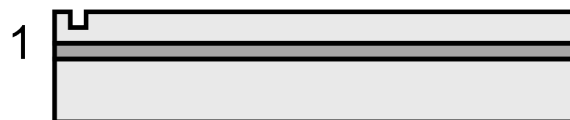
Thermal actuation (PRT)



- | | |
|--|--|
|  Undoped Si |  Al |
|  Doped Si |  Mo |
|  Oxide |  AlN |



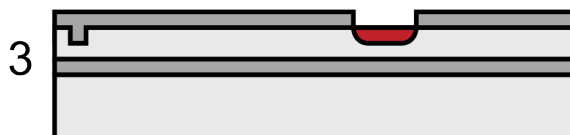
Probe Fabrication (PRPE)



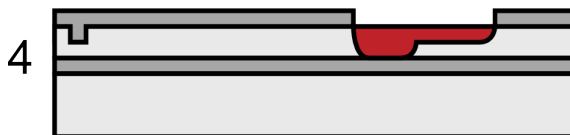
1 Pattern and etch alignment marks



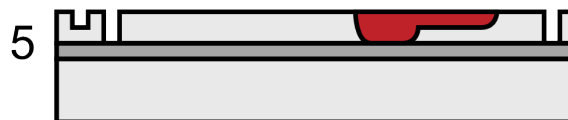
2 Oxidize to thin, deposit LTO, anneal, and open contact windows



3 Diffuse the contacts and strip the deposited PSG layer



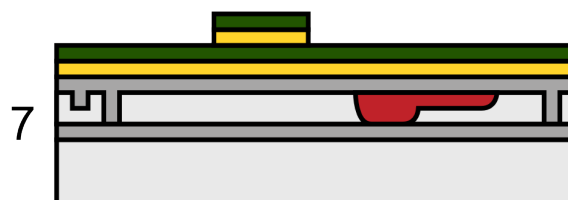
4 Open piezoresistor windows and diffuse the piezoresistors



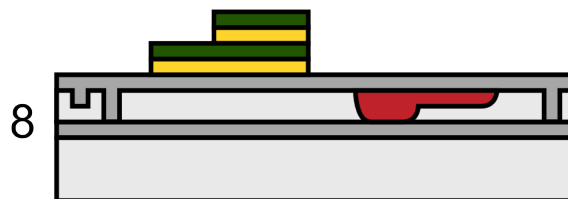
5 Strip all oxide and etch frontside



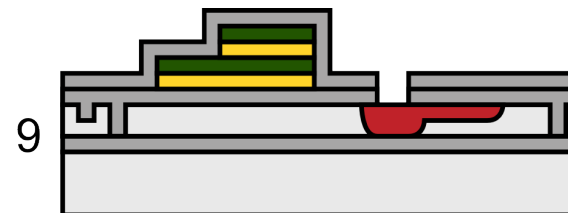
6 Deposit LTO and PE stack



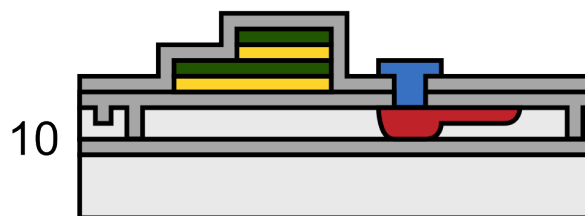
7 Pattern and etch top of PE stack



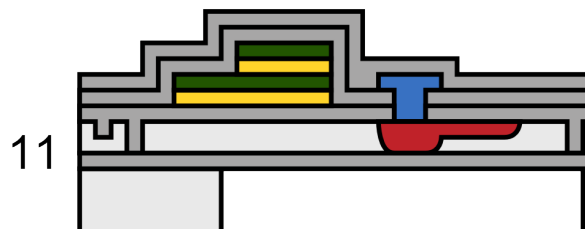
8 Pattern and etch bottom of PE stack



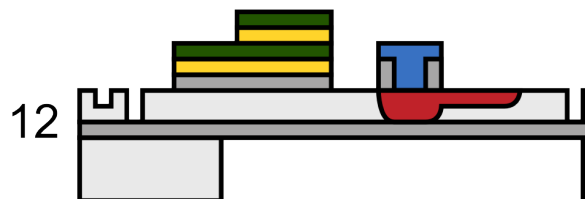
9 Deposit LTO and open contact vias



10 Deposit Al and etch back



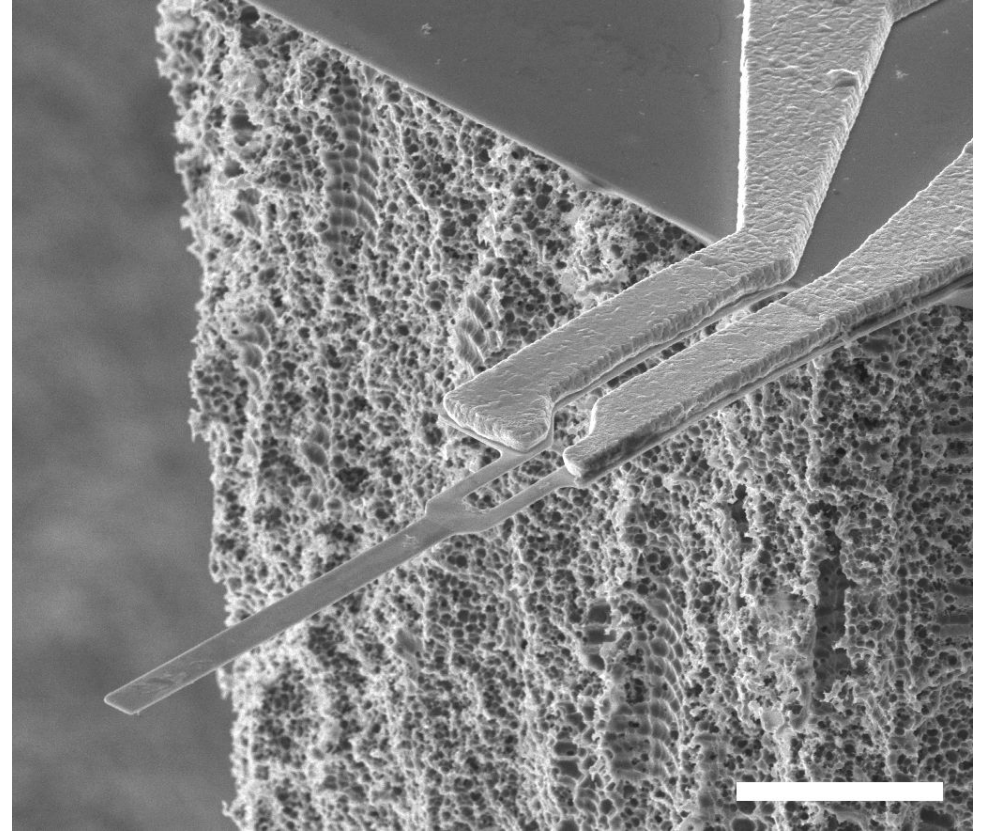
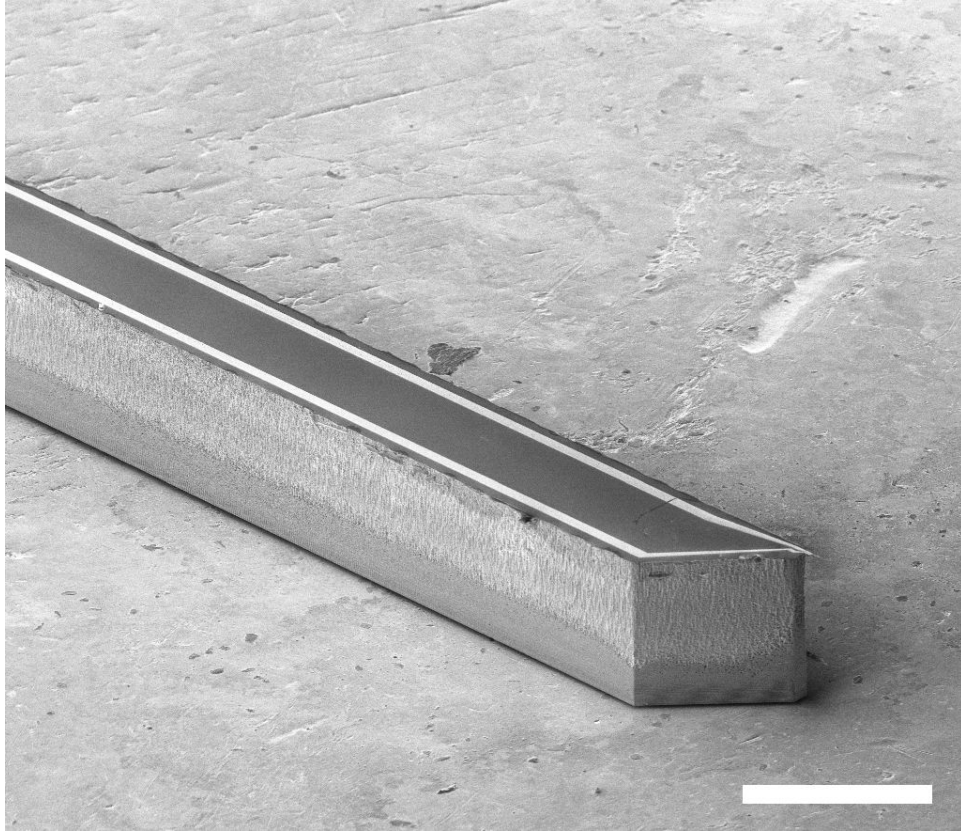
11 Seal with LTO, etch oxide cracks, bond to carriers, DRIE, debond



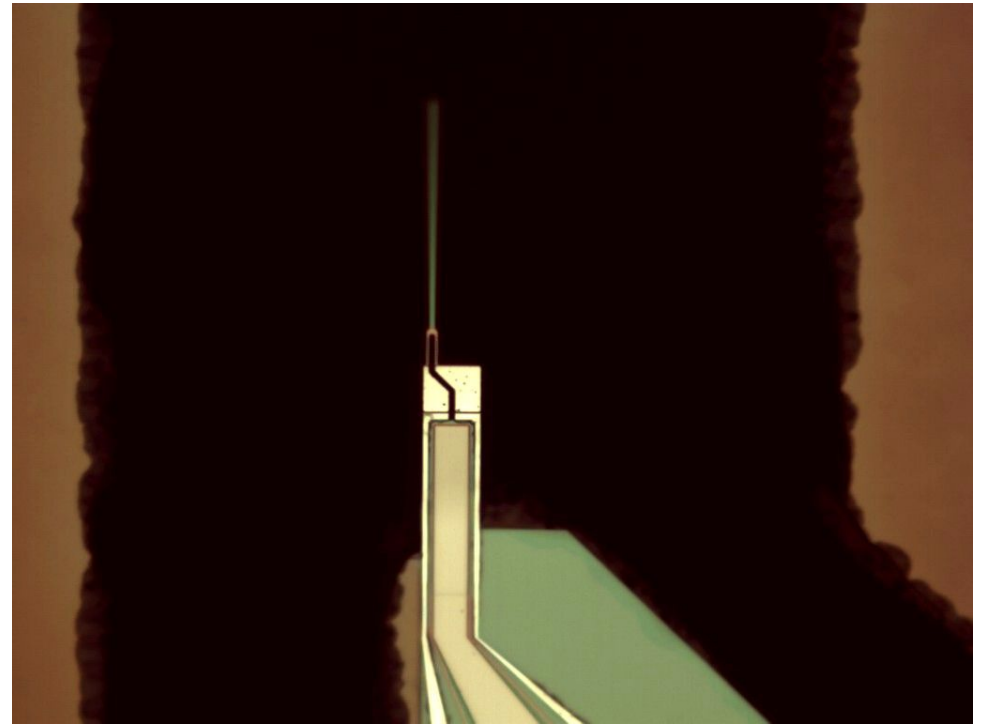
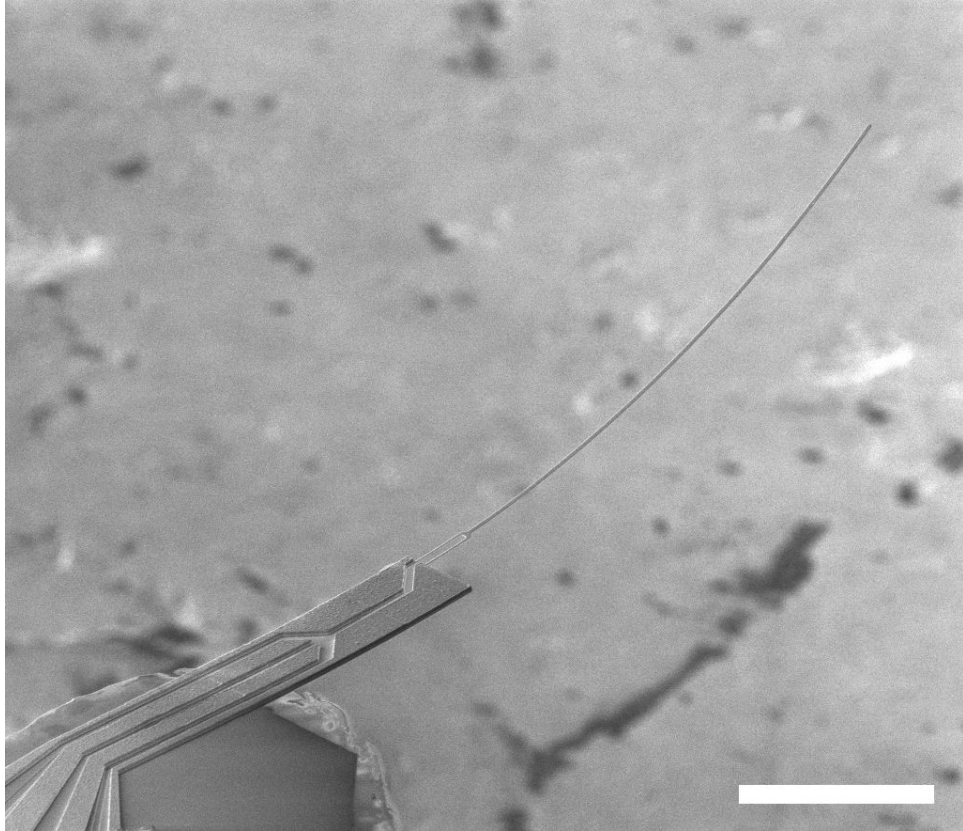
12 Cleanup DRIE polymer and release with HF vapor



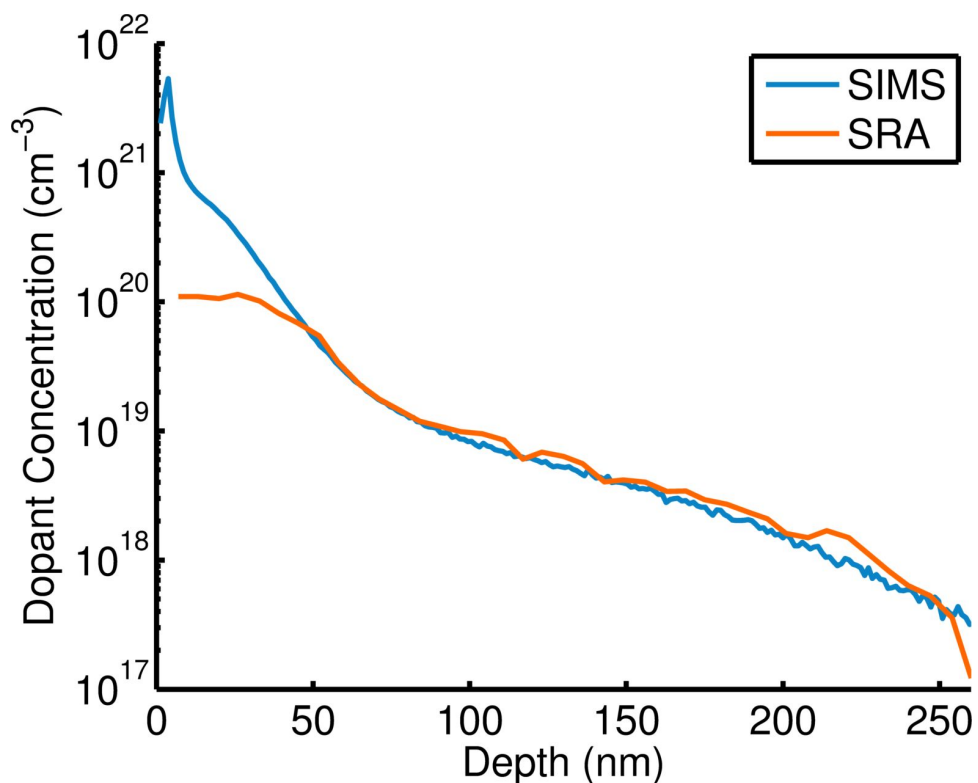
Finished Devices



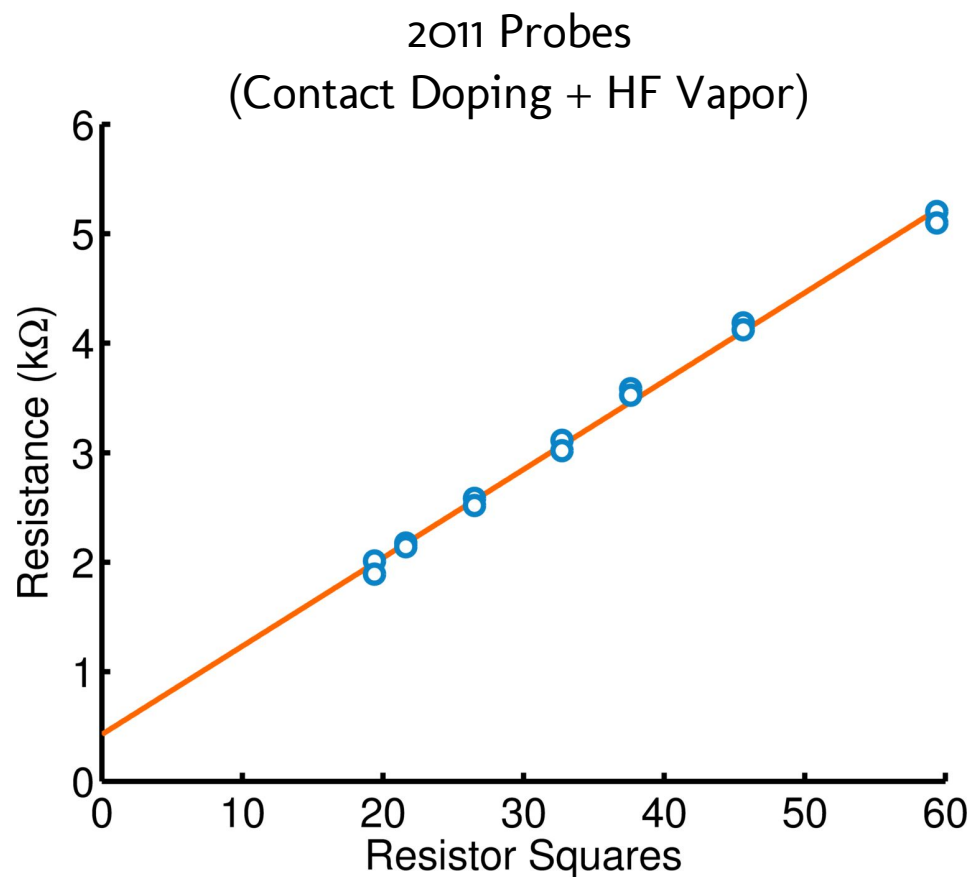
Finished Devices



Piezoresistor Electrical Properties

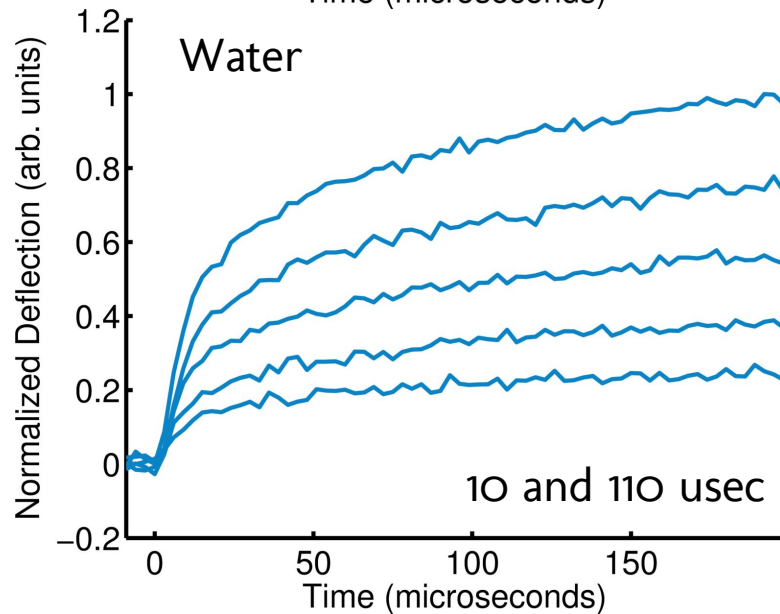
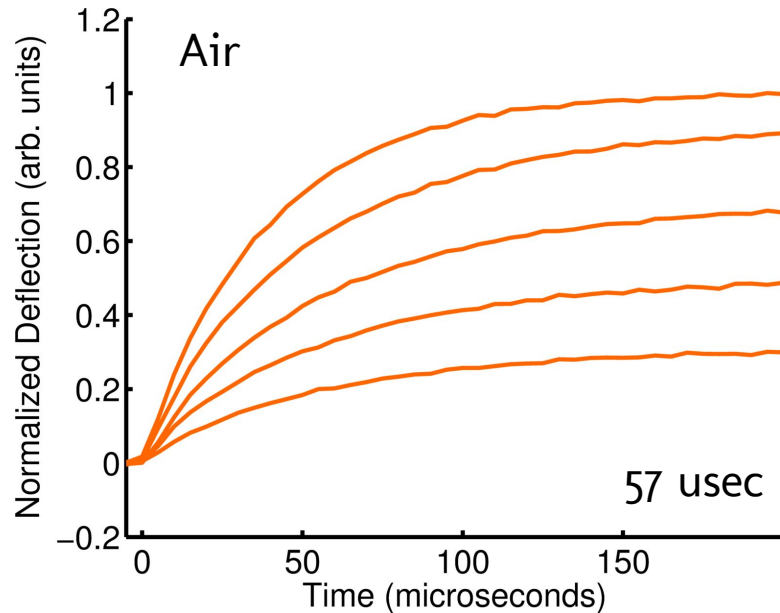


Single crystal Si, 800C/30min

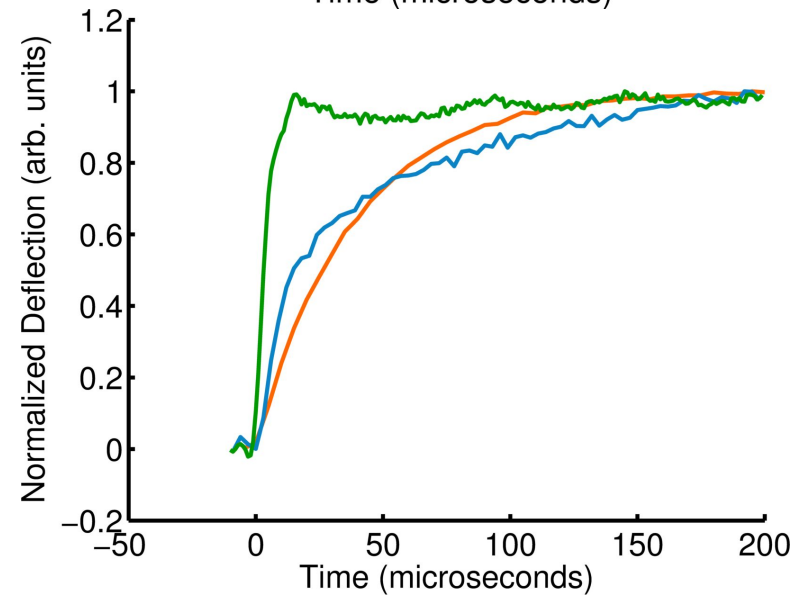
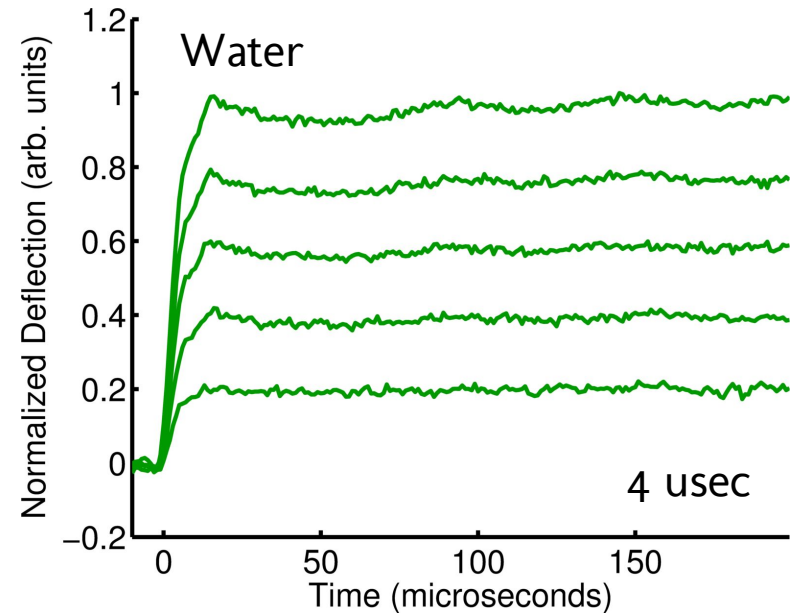


Actuator Step Response

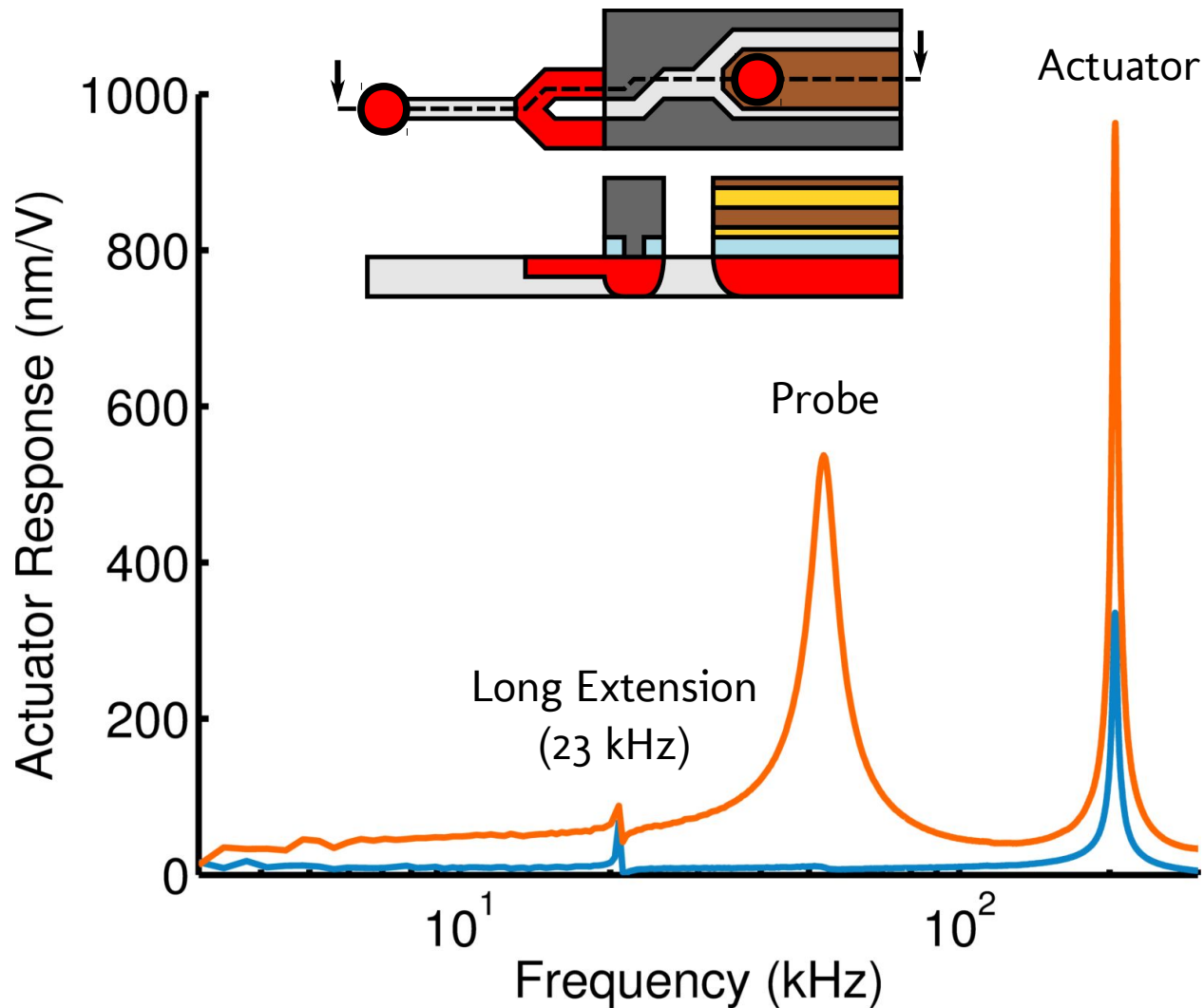
Thermal Actuator



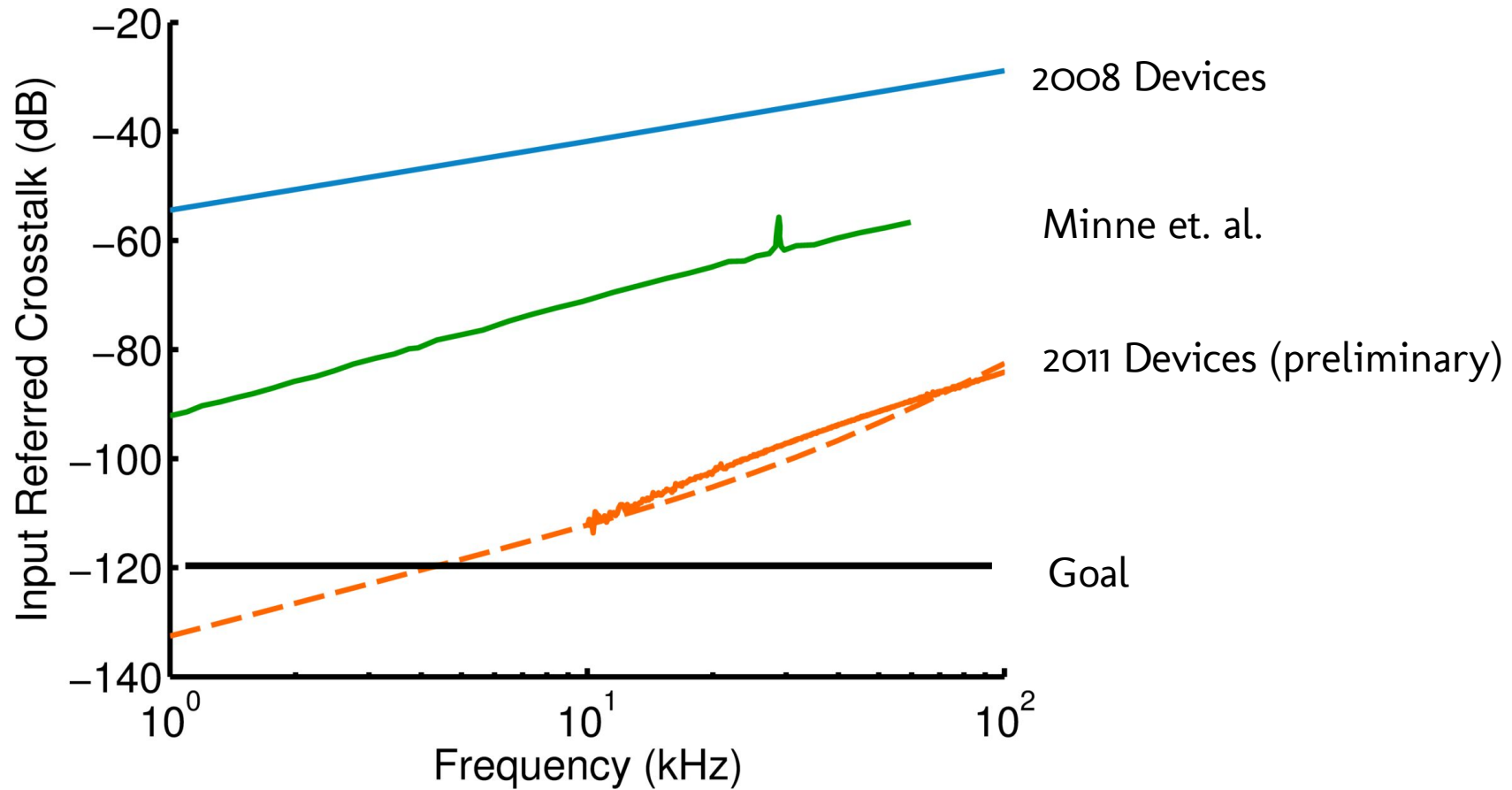
Piezoelectric Actuator



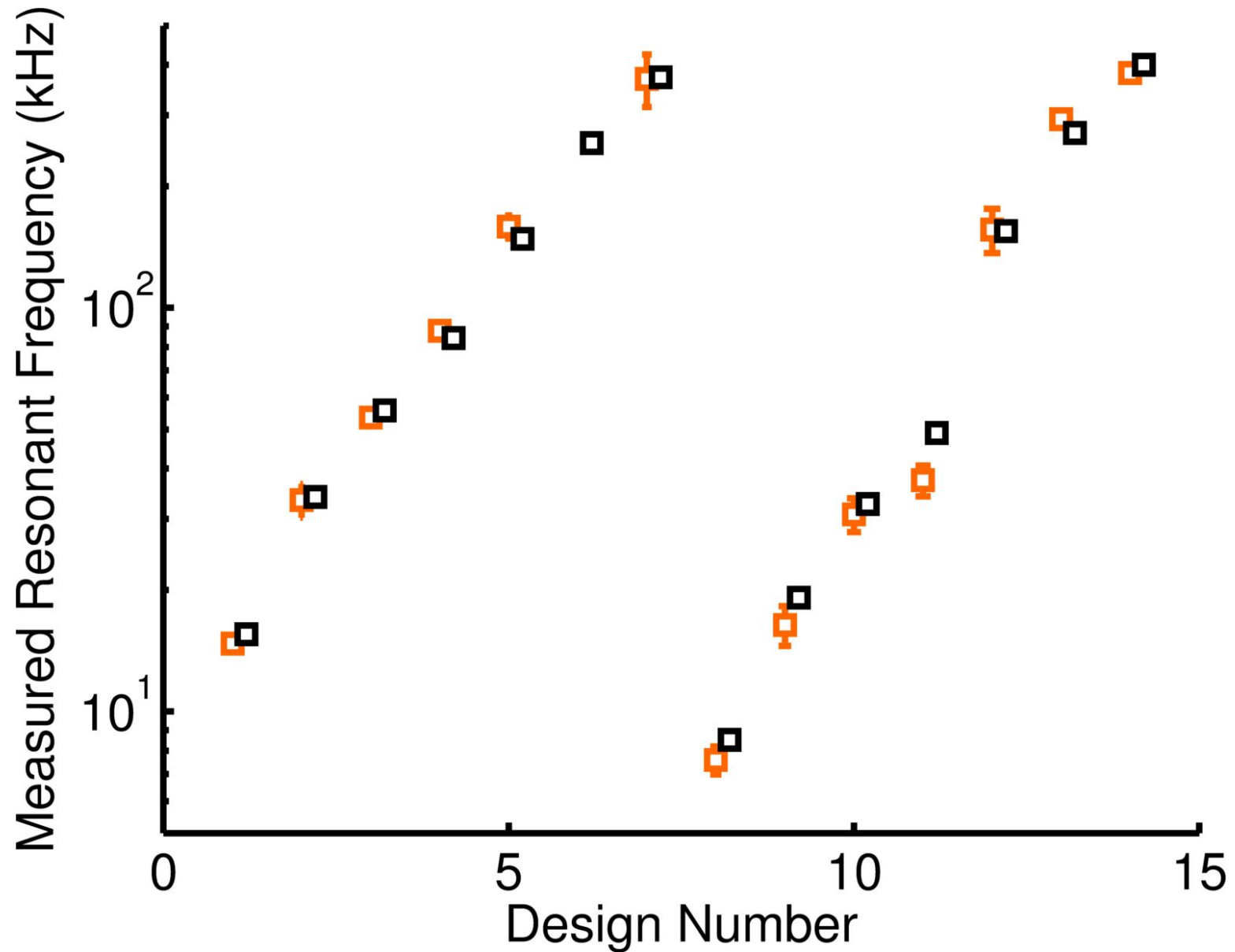
Actuator Frequency Response



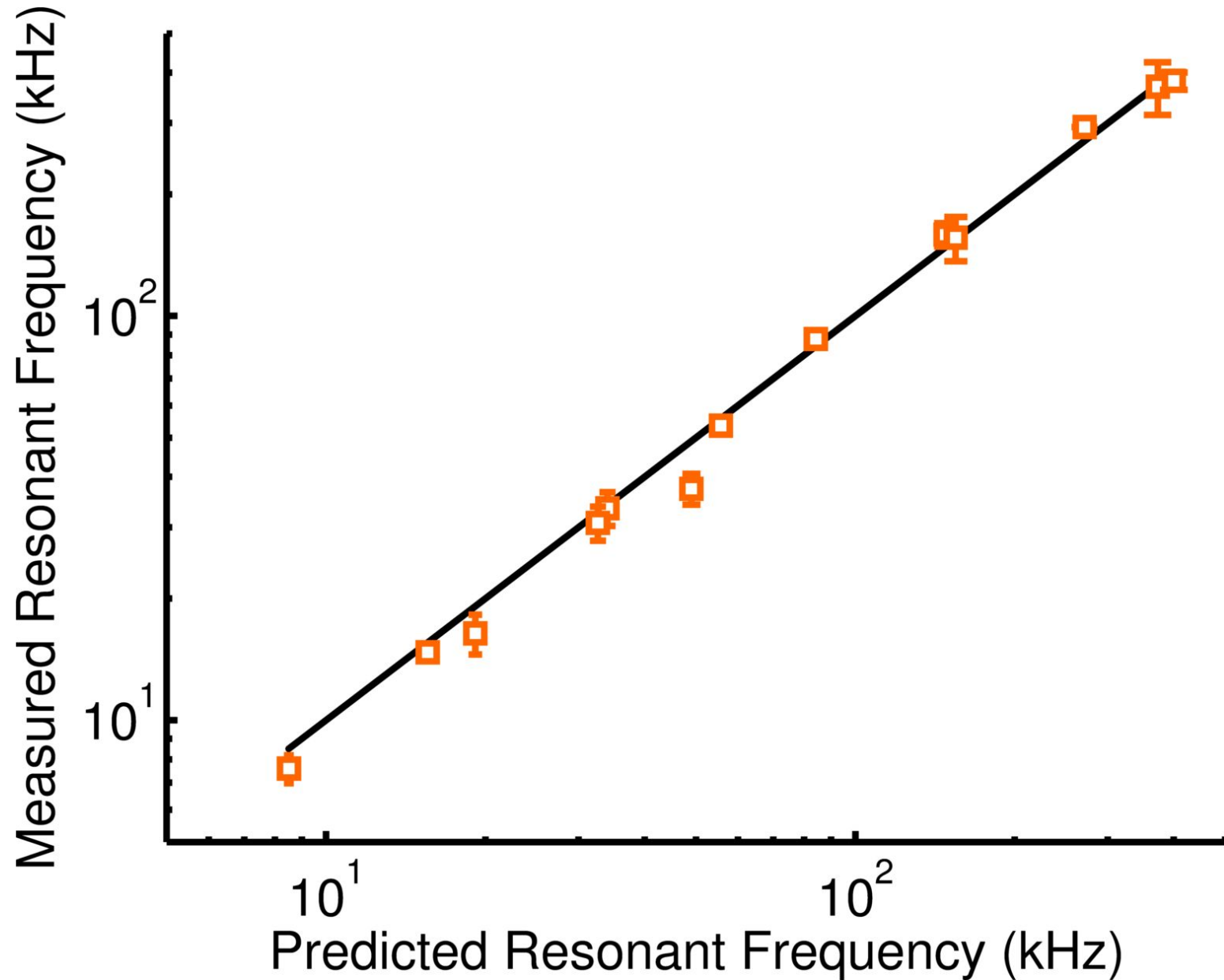
Capacitive Crosstalk



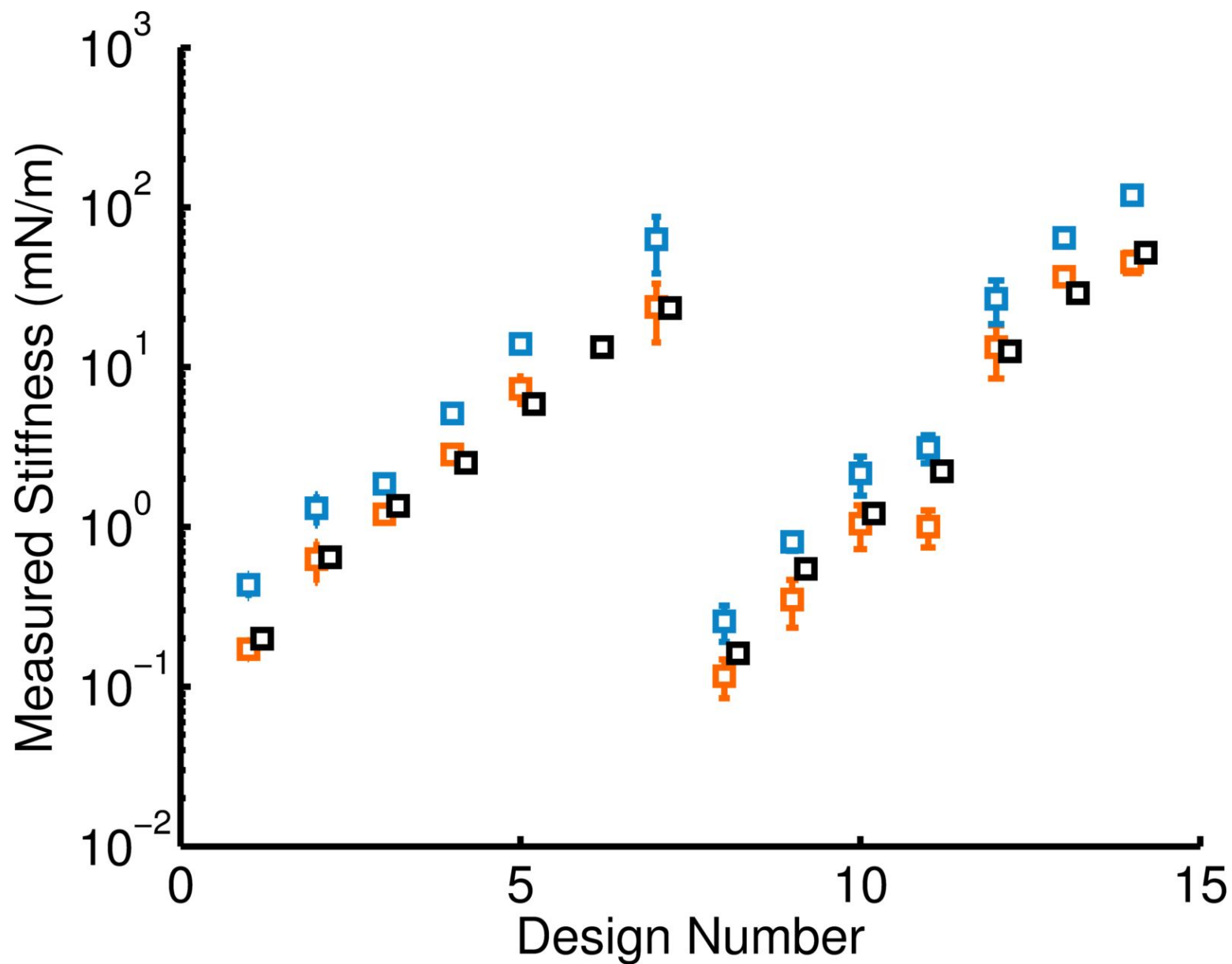
Resonant Frequency Data



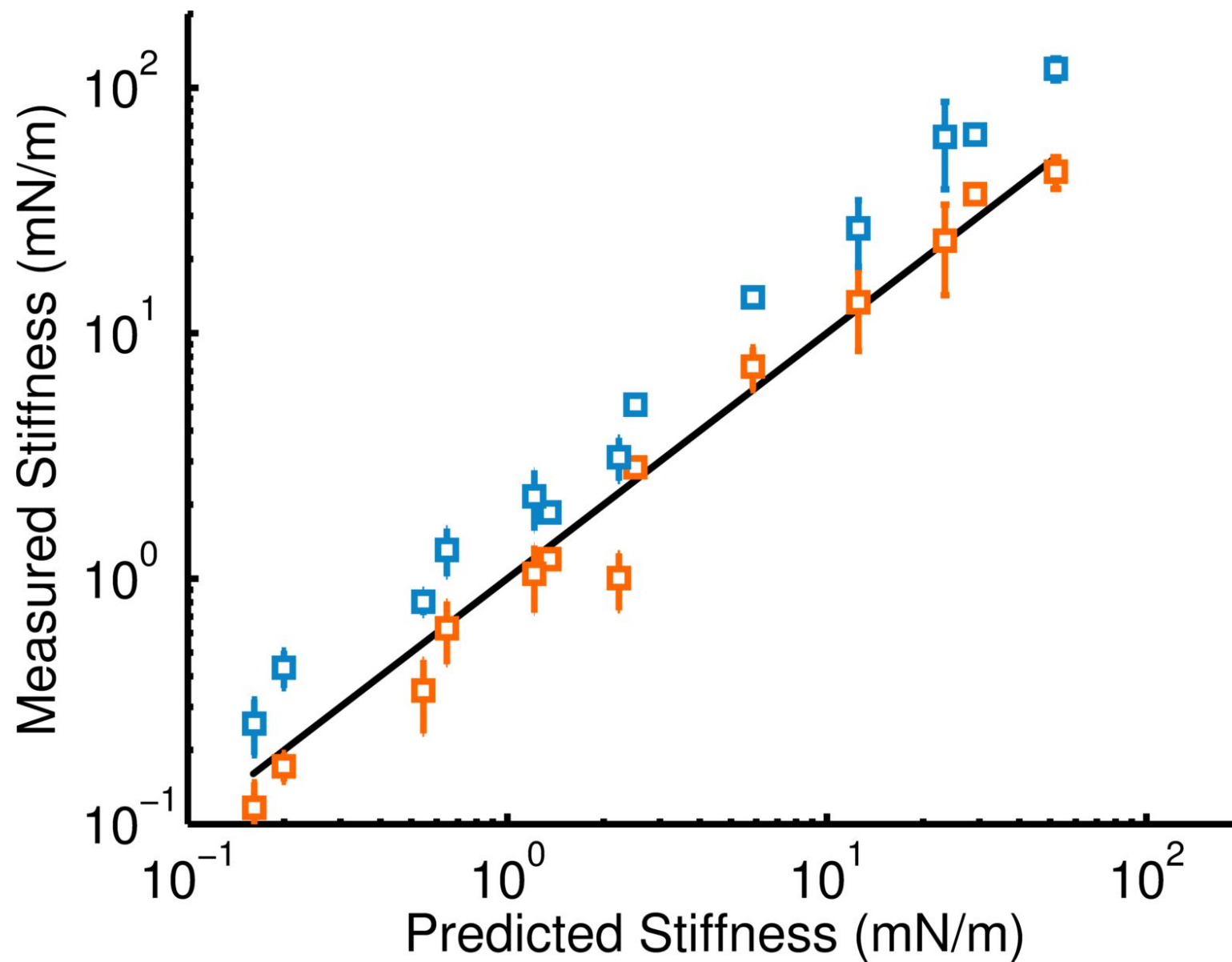
Resonant Frequency Data



Stiffness Data



Stiffness Data



Remaining Work

- Device characterization
 - Methods are fully developed. Currently testing more devices (at least 10-15 more)
 - Want to measure temperature via Raman (waiting on SNL training)
- Soft cantilever stiction upon exiting water
 - Plan on testing surface treatments
 - Discussions with Ginel Hill (who made < 0.1 mN/m probes) suggest O₂ plasma might work
- Hair cell experimental issues
 - Parylene coating is good as long as nothing touches it
 - Working on actuator-patch clamp crosstalk (alternative biasing and epoxy)
- Writing
 - Papers (device, methods)
 - Book (substantial overlap with the thesis)
 - Thesis (book work + experimental sections)